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Form PTO-1449 (Rev. 8-83) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO: 101328-148

APPLICATION NO: 09/512,942

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

APPLICANT:

Theodore H. Fedynyshyn

(Use several sheets if necessary)												E: 5, 2000		GROUP ART UNIT: 2852	
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CENTER 2 FILING DATE: TECHNULUGY CENTER ZATE FOLL GROUP ART UNIT: February 25, 2000 2852 U.S. PATENT DOCUMENTS **EXAMINER** DOCUMENT NUMBER INITIAL DATE FILING DATE IF NAME **CLASS SUBCLASS** APPROPRIATE* AA 3 8 0 3 04/74 Moreau 96 115R AB 2 0 2 6 9 7 05/80 Van Goethem et al. 430 306 FOREIGN PATENT DOCUMENTS TRANSLATION DOCUMENT NUMBER DATE COUNTRY SUBCLASS CLASS YES NO BA 1 0 2 0 3 8 01/89 Japan abst BB 0 3 2 4 2 7 9 03/91 Japan X OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.) CA Bruschi, P. et al., "Gas Sensing with Conducting Polymer Thin Film Resistors Obtained From Commercial Photoresist Patterns," Sens. Microsyst., Proc. Ital. Conf., Di Natale et al. (Editors), 69-73 (1996); Crivello, J. and Mao, Z., "Preparation and Cationic Photopolymerization of Organic-Inorganic Hybrid Matrixes," Chem. Mater., vol. 9, 1562-69 (1997); 껆 CC · Dagani, R., "Putting the 'Nano' into Composites," Chemical, 25-37 (June 7, 1999); M CD . Dumpich, G. et al., "Direct Writing of Metallic Nanostructures by Means of Metal Colloids," Materials Science Forum, vols. 287-8, 413-6 (1998); Kaplan, L.H. and Zimmerman, S.M., "Enhanced E-Beam Sensitivity of Resist," IBM Technical Disclosure Bulletin, vol. 21, no. 7, p. 2823 (December 1978); CF Mucha, et al., "Plasma Etching of Materials Used in Microelectronic Manufacturing," Introduction to Microlithography, L. Thompson et al., (editors), 449-64 (1994); CG 、 Pu, Jia-Ling et al., "Photobinding of Colloidal Particles by Means of Surface Modification," Journal of Imaging Science, vol.32, no. 3, 129-34 (May/June 1988); Pu, Jia-Ling et al., "Photobinding of Colloidal Particles by Means of Surface Modification. II. Surface Azido CH > Density and Dispersibility," Journal of Imaging Science, vol.32, no.6, 232-7 (November/December 1988); Examiner Date Considered: *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and considered. Include copy of this form with next communication to applicant. #873514v1 < imanage > -ids 1449.wpd